

Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 66302-006US1	Application No. 10/536,512
Information Disclosure Statement by Applicant (Use several sheets if necessary)		Applicant Jae-Hyun Kim	
		Filing Date May 25, 2005	Group Art Unit 1752

(37 CFR §1.98(b))

U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	6,033,830	03/07/2000	Sinta et al.			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AL	W000/54105	09/14/2000	WIPO				
	AM							
	AN							
	AO							
	AP							

Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
	AQ	Hwang S-H et al., "A novel organic bottom anti-reflective coating material for 193nm excimer laser lithography," Polymer, Elsevier Science Publishers B.V., GB, Vol. 41, No 17, August 2000 (2000-08), pages 6691-6694, XP004196891.
	AR	
	AS	
	AT	

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	